



IMST Technical Programme Agenda

Monday, January 19, 2004

- 1330hr – 1350hr Process Control in Micro-Embossing: A Review
David Hardt, MIT
- 1350hr – 1410hr An Analytical Solution on Convective and Diffusive Transport of Analyte in Laminar Flow of Microfluidic Slit
Y.C. Lam, NTU
- 1410hr – 1430hr Modeling Dielectric Erosion in Multi-Step Copper Chemical-Mechanical Polishing
Jung-Hoon Chun, MIT
- 1430hr – 1450hr Registration Using Projective Reconstruction for Augmented Reality Systems
M.L. Yuan, NUS
- 1450hr – 1510hr Characterization and Modeling of Chemical-Mechanical Polishing for Polysilicon Microstructures
Duane S. Boning, MIT
- 1510hr – 1530hr Pharmaceutical Properties of Nanoparticulate Formulation Composed of TPGS and PLGA for Controlled Delivery of Anticancer Drug
L. Mu, NTU
- 1530hr – 1545hr **Break**
- 1545hr – 1605hr A Study on the Boundary Conditions of 90° Paper Pop-up Structures
S. B. Tor, NTU
- 1605hr – 1625hr Non-linear mechanical behavior of polydimethylsiloxane (PDMS): application to the manufacture of microfluidic devices
Lallit Anand, MIT
- 1625hr – 1645hr InGaAsN/GaAs Quantum-well Laser Diodes
S.F. Yoon, NTU
- 1645hr – 1705hr On Dual Actuation in Atomic Force Microscopes
Kamal Youcef-Toumi, MIT
- 1705hr – 1725hr Focused ion beam direct fabrication of micro optical elements: features compared with laser beam and electron beam direct writing
Yongqi Fu, NTU

End of Day 1